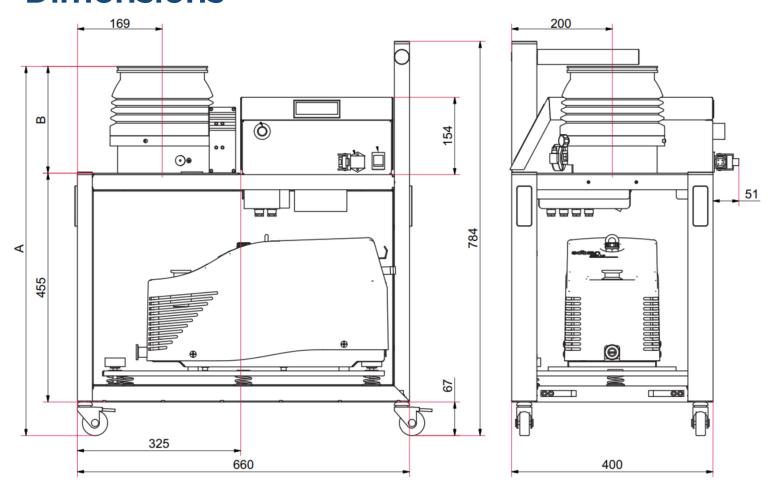
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## Pfeiffer HiCube 300 Pro Technical Specifications

Pumping station		HiCube 300 Pro	
Flange (in)		DN 100 ISO-K	DN 100 CF-F
Pumping speed for Nitrogen N <sub>2</sub>	l/s	260	260
Ultimate pressure			
with Piston pump XtraDry 150	mbar	< 1 · 10 <sup>-7</sup>	< 5 · 10 <sup>-10</sup>
with Rotary vane pump PentaLine	mbar	< 1 · 10-7	< 5 · 10 <sup>-10</sup>
Pumping speed backing pump at 50 Hz			
Piston pump XtraDry 150	m³/h	7.5	7.5
Rotary vane pump Penta 10	m³/h	11	11
Rotary vane pump Penta 20	m³/h	22	22
Rotary vane pump Penta 35	m³/h	34	34
Weight pumping station:1)			
with Piston pump XtraDry 150	kg	74.0	76.0
with Rotary vane pump Penta 10	kg	86.0	88.0
with Rotary vane pump Penta 20	kg	87.0	89.0
with Rotary vane pump Penta 35	kg	89.0	91.0
Power consumption			
with Piston pump XtraDry 150	W	850	850
with Rotary vane pump Penta 10	W	855	855
with Rotary vane pump Penta 20	W	1290	1290
with Rotary vane pump Penta 35	W	1775	1775

Ultimate pressure in a measuring dome 48 hours after bake-out, can be attained only with metallic seal of the high vacuum flange. (Ultimate pressure with elastomer seal (standard, not bakeable):  $< 1 \cdot 10^{-7}$  mbar.) <sup>1)</sup> without fore-vacuum safety valve

## Pfeiffer HiCube 300 Pro **Dimensions**



Dimensions	HiCube 300 Pro	HiCube 300 Pro
Flange	DN 100 ISO-K	DN 100 CF-F
A	716 mm	728 mm
В	195 mm	207 mm

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## Pfeiffer HiCube 300 Pro **Features & Benefits**

- especially characterized by its extremely fast pump-down times
- features connectivity for digital pressure sensors
- optimal combination of HiPace turbo pump & backing pump
- modular design affords simple customization for application
- service friendly due to accessibility of individual components
- integrated drive electronics
- easy data collection & analysis
- plug & play no installation or cabling required
- · robust engineering makes for long service life
- · optional forevacuum safety valve prevents venting in power failure
- direct connection of vacuum gauges possible

## **Applications**

- research & development accelerators analysis & surface physics
- vacuum process technology
  general vacuum applications

